

Jaume Esteve

List of Publications by Year in descending order

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218
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117625

34
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175258

52
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218
all docs

218
docs citations

218
times ranked

3600
citing authors

#	ARTICLE	IF	CITATIONS
1	Analysis of buried etch-stop layers in silicon by nitrogen-ion implantation. <i>Journal of Micromechanics and Microengineering</i> , 1993, 3, 143-145.	2.6	160
2	TMAH/IPA anisotropic etching characteristics. <i>Sensors and Actuators A: Physical</i> , 1993, 37-38, 737-743.	4.1	154
3	Monolithic CMOS MEMS Oscillator Circuit for Sensing in the Attogram Range. <i>IEEE Electron Device Letters</i> , 2008, 29, 146-148.	3.9	117
4	Electromechanical Nanogeneratorâ€œCell Interaction Modulates Cell Activity. <i>Advanced Materials</i> , 2017, 29, 1605048.	21.0	116
5	Permanently hydrophilic, piezoelectric PVDF nanofibrous scaffolds promoting unaided electromechanical stimulation on osteoblasts. <i>Nanoscale</i> , 2019, 11, 8906-8917.	5.6	109
6	Electromechanical model of a resonating nano-cantilever-based sensor for high-resolution and high-sensitivity mass detection. <i>Nanotechnology</i> , 2001, 12, 100-104.	2.6	106
7	Ultrasensitive mass sensor fully integrated with complementary metal-oxide-semiconductor circuitry. <i>Applied Physics Letters</i> , 2005, 87, 043507.	3.3	105
8	Integrated CMOS-MEMS with on-chip readout electronics for high-frequency applications. <i>IEEE Electron Device Letters</i> , 2006, 27, 495-497.	3.9	74
9	Batch fabrication of optical actuators using nanotubeâ€œelastomer composites towards refreshable Braille displays. <i>Journal of Micromechanics and Microengineering</i> , 2012, 22, 075009.	2.6	72
10	Tactile device based on opto-mechanical actuation of liquid crystal elastomers. <i>Sensors and Actuators A: Physical</i> , 2014, 208, 104-112.	4.1	72
11	Silicon chips detect intracellular pressure changes in living cells. <i>Nature Nanotechnology</i> , 2013, 8, 517-521.	31.5	68
12	Localised Actuation in Composites Containing Carbon Nanotubes and Liquid Crystalline Elastomers. <i>Macromolecular Rapid Communications</i> , 2011, 32, 1953-1959.	3.9	66
13	High-performance piezoresistive pressure sensors for biomedical applications using very thin structured membranes. <i>Measurement Science and Technology</i> , 1996, 7, 1195-1203.	2.6	62
14	The use of ferrofluids in micromechanics. <i>Sensors and Actuators A: Physical</i> , 2000, 84, 176-180.	4.1	62
15	Design of a modular micropump based on anodic bonding. <i>Journal of Micromechanics and Microengineering</i> , 1997, 7, 179-182.	2.6	61
16	Nanoscale imaging of buried topological defects with quantitative X-ray magnetic microscopy. <i>Nature Communications</i> , 2015, 6, 8196.	12.8	61
17	Design, fabrication, and characterization of a submicroelectromechanical resonator with monolithically integrated CMOS readout circuit. <i>Journal of Microelectromechanical Systems</i> , 2005, 14, 508-519.	2.5	59
18	Monolithic mass sensor fabricated using a conventional technology with attogram resolution in air conditions. <i>Applied Physics Letters</i> , 2007, 91, .	3.3	58

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19	Bending kinetics of a photo-actuating nematic elastomer cantilever. Applied Physics Letters, 2011, 99, .	3.3	58
20	Liquid-crystalline elastomer micropillar array for haptic actuation. Journal of Materials Chemistry C, 2013, 1, 5183.	5.5	58
21	Etching front control of <110 > strips for corner compensation. Sensors and Actuators A: Physical, 1993, 37-38, 727-732.	4.1	56
22	Determination of micromechanical properties of thin films by beam bending measurements with an atomic force microscope. Sensors and Actuators A: Physical, 1999, 74, 134-138.	4.1	55
23	Electrodeposited Co-Ni alloys for MEMS. Journal of Micromechanics and Microengineering, 2002, 12, 400-405.	2.6	52
24	Vibrational energy scavenging with Si technology electromagnetic inertial microgenerators. Microsystem Technologies, 2007, 13, 1655-1661.	2.0	50
25	Localized and distributed mass detectors with high sensitivity based on thin-film bulk acoustic resonators. Applied Physics Letters, 2006, 89, 033507.	3.3	45
26	Monolithic integration of mass sensing nano-cantilevers with CMOS circuitry. Sensors and Actuators A: Physical, 2003, 105, 311-319.	4.1	43
27	Intracellular Polysilicon Barcodes for Cell Tracking. Small, 2009, 5, 2433-2439.	10.0	43
28	Resonant silicon accelerometers in bulk micromachining technology-an approach. Journal of Microelectromechanical Systems, 1996, 5, 122-130.	2.5	42
29	Design and implementation of mechanical resonators for optimized inertial electromagnetic microgenerators. Microsystem Technologies, 2008, 14, 653-658.	2.0	42
30	Piezoresistive accelerometers for MCM package. Journal of Microelectromechanical Systems, 2002, 11, 794-801.	2.5	41
31	Development and Characterization of Co-Ni Alloys for Microsystems Applications. Journal of the Electrochemical Society, 2002, 149, C201.	2.9	40
32	Resonators with integrated CMOS circuitry for mass sensing applications, fabricated by electron beam lithography. Nanotechnology, 2005, 16, 98-102.	2.6	39
33	System on chip mass sensor based on polysilicon cantilevers arrays for multiple detection. Sensors and Actuators A: Physical, 2006, 132, 154-164.	4.1	38
34	BESOI-Based Integrated Optical Silicon Accelerometer. Journal of Microelectromechanical Systems, 2004, 13, 355-364.	2.5	37
35	A study of the undercutting characteristics in the TMAH-IPA system. Journal of Micromechanics and Microengineering, 1992, 2, 181-183.	2.6	36
36	Intracellular Silicon Chips in Living Cells. Small, 2010, 6, 499-502.	10.0	35

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37	Stress measurement by microRaman spectroscopy of polycrystalline silicon structures. <i>Journal of Micromechanics and Microengineering</i> , 1995, 5, 132-135.	2.6	34
38	Role of aluminum and HMTA in the hydrothermal synthesis of two-dimensional n-doped ZnO nanosheets. <i>Nano Energy</i> , 2019, 60, 817-826.	16.0	33
39	Design, fabrication and characterization of an externally actuated ON/OFF microvalve. <i>Sensors and Actuators A: Physical</i> , 2008, 147, 600-606.	4.1	31
40	Molybdenum alloy electrodeposits for magnetic actuation. <i>Electrochimica Acta</i> , 2006, 51, 3214-3222.	5.2	30
41	Nanocomposite photoactuators based on an ethylene vinyl acetate copolymer filled with carbon nanotubes. <i>Sensors and Actuators B: Chemical</i> , 2013, 186, 701-710.	7.8	29
42	Integration of NEMS resonators in a 65nm CMOS technology. <i>Microelectronic Engineering</i> , 2013, 110, 246-249.	2.4	29
43	Fabrication of cantilever based mass sensors integrated with CMOS using direct write laser lithography on resist. <i>Nanotechnology</i> , 2004, 15, S628-S633.	2.6	27
44	A novel embryo identification system by direct tagging of mouse embryos using silicon-based barcodes. <i>Human Reproduction</i> , 2011, 26, 96-105.	0.9	26
45	New bulk accelerometer for triaxial detection. <i>Sensors and Actuators A: Physical</i> , 1998, 66, 105-108.	4.1	25
46	Effect of silicon oxide, silicon nitride and polysilicon layers on the electrostatic pressure during anodic bonding. <i>Sensors and Actuators A: Physical</i> , 1998, 67, 181-184.	4.1	24
47	Fully integrated MIXLER based on VHF CMOS-MEMS clamped-clamped beam resonator. <i>Electronics Letters</i> , 2007, 43, 452.	1.0	24
48	Tactile Acuity Charts: A Reliable Measure of Spatial Acuity. <i>PLoS ONE</i> , 2014, 9, e87384.	2.5	24
49	Surface micromachining technology applied to the fabrication of a FET pressure sensor. <i>Journal of Micromechanics and Microengineering</i> , 1996, 6, 80-83.	2.6	23
50	Simple technology for bulk accelerometer based on bond and etch back silicon on insulator wafers. <i>Sensors and Actuators A: Physical</i> , 1998, 68, 299-302.	4.1	22
51	Twin-mass accelerometer optimization to reduce the package stresses. <i>Sensors and Actuators A: Physical</i> , 2000, 80, 199-207.	4.1	22
52	A platform for monolithic CMOS-MEMS integration on SOI wafers. <i>Journal of Micromechanics and Microengineering</i> , 2006, 16, 2203-2210.	2.6	22
53	Localized-mass detection based on thin-film bulk acoustic wave resonators (FBAR): Area and mass location aspects. <i>Sensors and Actuators A: Physical</i> , 2008, 142, 322-328.	4.1	22
54	Internalization and cytotoxicity analysis of silicon-based microparticles in macrophages and embryos. <i>Biomedical Microdevices</i> , 2010, 12, 371-379.	2.8	22

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55	Barcode tagging of human oocytes and embryos to prevent mix-ups in assisted reproduction technologies. <i>Human Reproduction</i> , 2014, 29, 18-28.	0.9	22
56	AFM lithography for the definition of nanometre scale gaps: application to the fabrication of a cantilever-based sensor with electrochemical current detection. <i>Nanotechnology</i> , 2004, 15, 771-776.	2.6	21
57	Geochemical and mineralogical characterization of surficial sediments from the Northern Rias: Implications for sediment provenance and impact of the source rocks. <i>Marine Geology</i> , 2012, 291-294, 63-72.	2.1	20
58	Suspended Planar Array Chips for Molecular Multiplexing at the Microscale. <i>Advanced Materials</i> , 2016, 28, 1449-1454.	21.0	20
59	Flow-through pH-ISFET + reference-ISE as integrated detector in automated FIA determinations. <i>Sensors and Actuators B: Chemical</i> , 1992, 7, 555-560.	7.8	19
60	Electrochemical deposition of Cu and Ni/Cu multilayers in Si Microsystem Technologies. <i>Sensors and Actuators A: Physical</i> , 2005, 123-124, 633-639.	4.1	19
61	Parasitic effect on silicon MEMS resonator model parameters. <i>Microelectronic Engineering</i> , 2007, 84, 1363-1368.	2.4	19
62	Selective Area Growth of High-Quality ZnO Nanosheets Assisted by Patternable AlN Seed Layer for Wafer-Level Integration. <i>Crystal Growth and Design</i> , 2016, 16, 5059-5066.	3.0	19
63	Passivation analysis of micromechanical silicon structures obtained by electrochemical etch stop. <i>Sensors and Actuators A: Physical</i> , 1993, 37-38, 744-750.	4.1	18
64	Silicon Microdevice for Emulsion Production Using Three-Dimensional Flow Focusing. <i>Journal of Microelectromechanical Systems</i> , 2007, 16, 1201-1208.	2.5	18
65	Optimization of a Piezoelectric Energy Harvester and Design of a Charge Pump Converter for CMOS-MEMS Monolithic Integration. <i>Sensors</i> , 2019, 19, 1895.	3.8	18
66	Fabrication and characterization of a twin-mass accelerometer. <i>Sensors and Actuators A: Physical</i> , 1994, 43, 115-119.	4.1	17
67	Fully CMOS integrated low voltage 100 MHz MEMS resonator. <i>Electronics Letters</i> , 2005, 41, 1327.	1.0	17
68	Nanomagnets with high shape anisotropy and strong crystalline anisotropy: perspectives on magnetic force microscopy. <i>Nanotechnology</i> , 2011, 22, 505301.	2.6	17
69	Stress mapping on the porous silicon microcapsules by Raman microscopy. <i>Microelectronic Engineering</i> , 2012, 98, 488-491.	2.4	17
70	Non-destructive in situ test for anodic bonding. <i>Sensors and Actuators A: Physical</i> , 1997, 60, 176-180.	4.1	16
71	Linear and non-linear behavior of mechanical resonators for optimized inertial electromagnetic microgenerators. <i>Microsystem Technologies</i> , 2009, 15, 1217-1223.	2.0	16
72	High-frequency sensor technologies for inertial force detection based on thin-film bulk acoustic wave resonators (FBAR). <i>Microelectronic Engineering</i> , 2009, 86, 1254-1257.	2.4	16

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73	Zero-level packaging of MEMS in standard CMOS technology. <i>Journal of Micromechanics and Microengineering</i> , 2010, 20, 064009.	2.6	16
74	Improving Morphological Quality and Uniformity of Hydrothermally Grown ZnO Nanowires by Surface Activation of Catalyst Layer. <i>Nanoscale Research Letters</i> , 2017, 12, 51.	5.7	16
75	Application of nickel electroless plating to the fabrication of low-cost backside contact ISFETs. <i>Sensors and Actuators B: Chemical</i> , 1995, 27, 336-340.	7.8	14
76	New FET accelerometer based on surface micromachining. <i>Sensors and Actuators A: Physical</i> , 1997, 61, 342-345.	4.1	14
77	Versatile micropipette technology based on deep reactive ion etching and anodic bonding for biological applications. <i>Journal of Micromechanics and Microengineering</i> , 2009, 19, 105013.	2.6	14
78	Stress in low pressure chemical vapour deposition polycrystalline silicon thin films deposited below 0.1 Torr. <i>Sensors and Actuators A: Physical</i> , 1993, 37-38, 723-726.	4.1	13
79	Application of simple thioether ionophores to silver ion-selective CHEMFETs. <i>Sensors and Actuators B: Chemical</i> , 1995, 27, 321-324.	7.8	13
80	Test microstructures for measurement of SiC thin film mechanical properties. <i>Journal of Micromechanics and Microengineering</i> , 1999, 9, 190-193.	2.6	13
81	Highly Anisotropic Suspended Planar Array Chips with Multidimensional Submicrometric Biomolecular Patterns. <i>Advanced Functional Materials</i> , 2017, 27, 1605912.	14.9	13
82	Electrical stimulation of cells through photovoltaic microcell arrays. <i>Nano Energy</i> , 2018, 51, 571-578.	16.0	13
83	Analysis of nonlinearity in high sensitivity piezoresistive pressure sensors. <i>Sensors and Actuators A: Physical</i> , 1993, 37-38, 790-795.	4.1	12
84	New technology for easy and fully IC-compatible fabrication of backside-contacted ISFETs. <i>Sensors and Actuators B: Chemical</i> , 1995, 24, 228-231.	7.8	12
85	A new process for releasing micromechanical structures in surface micromachining. <i>Journal of Micromechanics and Microengineering</i> , 1996, 6, 36-39.	2.6	12
86	Nondestructive Anodic Bonding Test. <i>Journal of the Electrochemical Society</i> , 1997, 144, L108-L110.	2.9	12
87	Analytical and Finite-Element Modeling of Localized-Mass Sensitivity of Thin-Film Bulk Acoustic-Wave Resonators (FBAR). <i>IEEE Sensors Journal</i> , 2009, 9, 892-901.	4.7	12
88	Polymer micromixers bonded to thermoplastic films combining soft lithography with plasma and aptes treatment processes. <i>Journal of Polymer Science Part A</i> , 2013, 51, 59-70.	2.3	12
89	Non-linear nanoscale piezoresponse of single ZnO nanowires affected by piezotronic effect. <i>Nanotechnology</i> , 2021, 32, 025202.	2.6	12
90	Influence of the degradation on the surface states and electrical characteristics of EOS structures. <i>Surface Science</i> , 1991, 251-252, 364-368.	1.9	11

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91	Piezoresistive accelerometers for MCM-package - Part II:The packaging. Journal of Microelectromechanical Systems, 2005, 14, 806-811.	2.5	11
92	Focused ion beam-assisted technology in sub-picolitre micro-dispenser fabrication. Journal of Micromechanics and Microengineering, 2008, 18, 075021.	2.6	11
93	Heat-controlled micropillar array device for microsystems technology. Soft Matter, 2017, 13, 7264-7272.	2.7	11
94	Study of Galfenol direct cytotoxicity and remote microactuation in cells. Biomaterials, 2017, 139, 67-74.	11.4	11
95	A New Single-Sensor Magnetic Field Gradiometer. Sensor Letters, 2009, 7, 563-570.	0.4	11
96	Characterization and Passivation Effects of an Optical Accelerometer Based on Antiresonant Waveguides. IEEE Photonics Technology Letters, 2004, 16, 233-235.	2.5	10
97	Si technology based microinductive devices for biodetection applications. Sensors and Actuators A: Physical, 2006, 132, 499-505.	4.1	10
98	Reduction of droplet-size dispersion in parallel flow-focusing microdevices using a passive method. Journal of Micromechanics and Microengineering, 2009, 19, 045029.	2.6	10
99	Design and characterization of a magnetic digital flow regulator. Sensors and Actuators A: Physical, 2010, 162, 107-115.	4.1	10
100	Thermally driven micromechanical bridge resonators. Sensors and Actuators A: Physical, 1994, 42, 680-684.	4.1	9
101	A technology for the monolithic fabrication of a pressure sensor and related circuitry. Sensors and Actuators A: Physical, 1995, 46, 133-136.	4.1	9
102	Cathodic Debond of Anodically Bonded Silicon to Glass Wafers. Electrochemical and Solid-State Letters, 1999, 3, 392.	2.2	9
103	Ion beam synthesis of polycrystalline SiC on SiO ₂ structures for MEMS applications. Journal of Micromechanics and Microengineering, 2000, 10, 152-156.	2.6	9
104	Protection of MOS capacitors during anodic bonding. Journal of Micromechanics and Microengineering, 2002, 12, 361-367.	2.6	9
105	Technological aspects on the fabrication of silicon-based optical accelerometer with ARROW structures. Sensors and Actuators A: Physical, 2004, 110, 395-400.	4.1	9
106	Cantilever based mems for multiple mass sensing. , 0, , .		9
107	Time-Resolved Evaporation Rate of Attoliter Glycerine Drops Using On-Chip CMOS Mass Sensors Based on Resonant Silicon Micro Cantilevers. IEEE Nanotechnology Magazine, 2007, 6, 509-512.	2.0	9
108	Focused-ion-beam-assisted tuning of thin-film bulk acoustic wave resonators (FBARs). Journal of Micromechanics and Microengineering, 2007, 17, 2380-2389.	2.6	9

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109	Microinductive Signal Conditioning With Resonant Differential Filters: High-Sensitivity Biodetection Applications. IEEE Transactions on Instrumentation and Measurement, 2007, 56, 1590-1595.	4.7	9
110	Thin-Film Bulk Acoustic Wave Resonator Floating Above CMOS Substrate. IEEE Electron Device Letters, 2008, 29, 28-30.	3.9	9
111	Thin-Film Piezoelectric MEMS Transducer Suitable for Middle-Ear Audio Prostheses. Journal of Microelectromechanical Systems, 2012, 21, 1452-1463.	2.5	9
112	ZnO Nanosheet-Coated TiZrPdSiNb Alloy as a Piezoelectric Hybrid Material for Self-Stimulating Orthopedic Implants. Biomedicine, 2021, 9, 352.	3.2	9
113	Micromachined optical fiber current sensor. Applied Optics, 1999, 38, 5298.	2.1	8
114	Microporous silicon for CMOS compatible MST. , 0, , .		8
115	On-line determination of the degradation of ISFET chemical sensors. Sensors and Actuators B: Chemical, 1993, 15, 218-222.	7.8	7
116	Three-dimensional structures obtained by double diffusion and electrochemical etch stop. Journal of Micromechanics and Microengineering, 1993, 3, 141-142.	2.6	7
117	Nanometer scale gaps for capacitive transduction improvement on RF-MEMS resonators. Microelectronic Engineering, 2007, 84, 1384-1387.	2.4	7
118	Fabrication of nanogaps for MEMS prototyping using focused ion beam as a lithographic tool and reactive ion etching pattern transfer. Microelectronic Engineering, 2007, 84, 1215-1218.	2.4	7
119	Chemical Functionalization of Polysilicon Microparticles for Single-Cell Studies. Langmuir, 2011, 27, 8302-8308.	3.5	7
120	Technological development of intracellular polysiliconâ€“chromiumâ€“gold chips for orthogonal chemical functionalization. Sensors and Actuators B: Chemical, 2015, 209, 212-224.	7.8	7
121	Suspended Silicon Microphotodiodes for Electrochemical and Biological Applications. Small, 2017, 13, 1701920.	10.0	7
122	Self-activated microbatteries to promote cell death through local electrical stimulation. Nano Energy, 2021, 83, 105852.	16.0	7
123	Growth and characterization of shape memory alloy thin films for Si microactuator technologies. Journal of Materials Science: Materials in Electronics, 2001, 12, 323-326.	2.2	6
124	Electrochemical deposition of metal layers and structures for Si-based microsystems. Sensors and Actuators A: Physical, 2002, 99, 41-44.	4.1	6
125	Resonance frequency dependence on out-of-plane forces for square silicon membranes: Applications to a MEMS gradiometer. Sensors and Actuators A: Physical, 2010, 163, 75-81.	4.1	6
126	Nano opto-mechanical systems (NOMS) as a proposal for tactile displays. Proceedings of SPIE, 2011, , .	0.8	6

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127	Integration of Liquid-Crystalline Elastomers in MEMS/MOEMS. , 2016, , 553-582.		6
128	Biocompatibility and Electrical Stimulation of Skeletal and Smooth Muscle Cells Cultured on Piezoelectric Nanogenerators. International Journal of Molecular Sciences, 2022, 23, 432.	4.1	6
129	Time-dependent response of interface states determined by using differential isothermal transient spectroscopy. Applied Surface Science, 1987, 30, 120-126.	6.1	5
130	Fluidic components based on ferrofluids. , 0, , .		5
131	Modeling the Thermal Actuation in a Thermo-Pneumatic Micropump. Journal of Electronic Packaging, Transactions of the ASME, 2003, 125, 527-530.	1.8	5
132	Nanocantilever based mass sensor integrated with CMOS circuitry. , 0, , .		5
133	<title>CMOS degradation effects due to electron beam lithography in smart NEMS fabrication</title>. , 2005, 5836, 667.		5
134	Focused-Ion-Beam-Assisted Magnet Fabrication and Manipulation for Magnetic Field Detection Applications. ACS Applied Materials & Interfaces, 2009, 1, 527-531.	8.0	5
135	Opto-mechanical parameters of liquid crystals elastomers with carbon nanotubes. Proceedings of SPIE, 2011, , .	0.8	5
136	Gas-Pressure Molding-Based Fabrication of Smart Actuators from Nematic Liquid-Crystalline Elastomer. Macromolecular Materials and Engineering, 2014, 299, 1163-1169.	3.6	5
137	Silicon-nanowire based attachment of silicon chips for mouse embryo labelling. Lab on A Chip, 2015, 15, 1508-1514.	6.0	5
138	Anisotropic etch-stop properties of nitrogen-implanted silicon. Sensors and Actuators A: Physical, 1994, 45, 219-225.	4.1	4
139	SOI-silicon as structural layer for NEMS applications. , 2003, , .		4
140	High-sensitivity capacitive readout system for resonant submicrometer-scale cantilevers based sensors. , 0, , .		4
141	Electrical detection of multiple resonant modes in a CMOS-MEMS cantilever. Microelectronic Engineering, 2007, 84, 1374-1378.	2.4	4
142	Light-actuated CNT-doped elastomer blisters towards braille dots. , 2011, , .		4
143	Sensitivity of thin-film bulk acoustic resonators (FBAR) to localized mechanical forces. Journal of Micromechanics and Microengineering, 2013, 23, 065024.	2.6	4
144	Novel optimized design of a piezoelectric energy harvester in a package for low amplitude vibrations. Journal of Physics: Conference Series, 2013, 476, 012042.	0.4	4

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145	Combination of PDMS microfilters and micromixers based on flexible thermoplastic films for size sorting and mixing of microparticles. Journal of Applied Polymer Science, 2015, 132, .	2.6	4
146	Modelization and fabrication of ISFET based sensors. Microelectronic Engineering, 1991, 15, 423-426.	2.4	3
147	Structural characterisation of nitrogen ion implantation into silicon for sensor technology. Nuclear Instruments & Methods in Physics Research B, 1993, 80-81, 702-705.	1.4	3
148	Epitaxial Growth of \hat{I}^2 -SiC on Ion-Beam Synthesized \hat{I}^2 -SiC: Structural Characterization. Materials Science Forum, 2000, 338-342, 309-312.	0.3	3
149	Adapting MCM-D technology to a piezoresistive accelerometer packaging. Journal of Micromechanics and Microengineering, 2003, 13, S41-S44.	2.6	3
150	Automated on-wafer extraction of equivalent circuit parameters in thin-film bulk acoustic wave resonators and substrate. Microwave and Optical Technology Letters, 2008, 50, 4-7.	1.4	3
151	Nanomagnet fabrication on FBAR for magnetic sensor applications. , 2009, , .		3
152	Microstamped opto-mechanical actuator for tactile displays. , 2011, , .		3
153	Internalization and Viability Studies of Suspended Nanowire Silicon Chips in HeLa Cells. Nanomaterials, 2020, 10, 893.	4.1	3
154	<title>Diffusion-induced dislocations in highly boron-doped silicon layers used for bulk micromachining applications</title>. , 1998, 3511, 88.		2
155	Ion beam synthesis of n-type doped SiC layers. Applied Surface Science, 2001, 184, 367-371.	6.1	2
156	A read-out strategy and circuit design for high frequency MEMS resonators. , 0, , .		2
157	Sensor based on arrays of sub-micrometer scale resonant silicon cantilevers integrated monolithically with CMOS circuitry. , 0, , .		2
158	P2K-2 Sensitivity Considerations in Localized Mass Detection Based on Thin-Film Bulk Acoustic Wave Resonators. , 2006, , .		2
159	12E-1 Accelerometer Based on Thin-Film Bulk Acoustic Wave Resonators. Proceedings IEEE Ultrasonics Symposium, 2007, , .	0.0	2
160	Magnetically actuated microvalve for disposable drug infusor. , 2007, , .		2
161	Linear and non linear behavior of mechanical resonators for optimized inertial electromagnetic microgenerators. , 2008, , .		2
162	Focus ion beam micromachined glass pipettes for cell microinjection. Biomedical Microdevices, 2010, 12, 311-316.	2.8	2

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163	In situ MEMS gradiometer with nanometer-resolution optical detection system. Sensors and Actuators A: Physical, 2010, 159, 33-40.	4.1	2
164	Electromagnetic harvester device for scavenging ambient mechanical energy with slow, variable, and randomness nature. , 2011, , .		2
165	Front Matter: Volume 8107. Proceedings of SPIE, 2011, , .	0.8	2
166	Education and dissemination strategies of photoactuation as a novel phenomenon. Proceedings of SPIE, 2011, , .	0.8	2
167	DRIE based technology for 3D silicon barcodes fabrication. Sensors and Actuators B: Chemical, 2011, 154, 181-184.	7.8	2
168	Integration of piezoelectric energy scavengers with FBAR resonators for the miniaturization of autonomous wireless sensors nodes. , 2012, , .		2
169	Towards the Monolithic Integration of Converter Circuitry and Piezoelectric MEMS Energy Harvesters. Proceedings (mdpi), 2018, 2, .	0.2	2
170	ac capacitance and conductance measurements of two-terminal metal-oxide-semiconductor capacitors on silicon-on-insulator substrates. Journal of Applied Physics, 1991, 70, 5111-5113.	2.5	1
171	Passivation analysis of (100) surfaces by anodic oxidation in aqueous KOH. Journal of Micromechanics and Microengineering, 1993, 3, 138-140.	2.6	1
172	Electrostatically controlled multi-purpose torsional structures obtained on monocrystalline silicon. Journal of Micromechanics and Microengineering, 1996, 6, 103-104.	2.6	1
173	Structural and Micromechanical Assessment of Electrochemically Grown Metal Layers for Si Magnetic Microactuators. Materials Research Society Symposia Proceedings, 2000, 657, 421.	0.1	1
174	Differential injection analysis based on backside-contacted ISFETs. , 2001, , .		1
175	<title>Large-signal model of a resonating cantilever-based transducer for system level electrical simulation</title>. , 2005, , .		1
176	FEM of anodic bonding test structures. , 0, , .		1
177	Nanocantilevers with integrated CMOS: effects of electron beam lithography on NMOS transistors. , 0, , .		1
178	CMOS-SOI platform for monolithic integration of crystalline silicon MEMS. Electronics Letters, 2006, 42, 800.	1.0	1
179	Instantaneous de-embedding of the on-wafer equivalent-circuit parameters of acoustic resonator (FBAR) for integrated circuit applications. , 2007, , .		1
180	Design and implementation of mechanical resonators for optimized inertial electromagnetic microgenerators. , 2007, , .		1

#	ARTICLE	IF	CITATIONS
181	Monolithic 0.35- μ m CMOS Cantilever for Mass Sensing in the Attogram Range with Self-Excitation. , 2007, , .		1
182	Implementation of ion-beam techniques in microsystems manufacturing: opportunities in cell biology. Proceedings of SPIE, 2009, , .	0.8	1
183	Sharpened transparent micronozzle fabrication for cell membrane piercing. Proceedings of SPIE, 2009, , .	0.8	1
184	DRIE based technology for 3D silicon barcodes fabrication. Procedia Chemistry, 2009, 1, 800-803.	0.7	1
185	Directed Fracture for the Fabrication of Free- μ Standing Multilayered Submicrometer Structures. Small, 2011, 7, 558-562.	10.0	1
186	Nematic opto-mechanical actuators for the fabrication of refreshable tactile systems. , 2013, , .		1
187	Electrospun nanobridges towards self-heated gas sensors with enhanced sensitivity. Journal of Physics: Conference Series, 2013, 421, 012002.	0.4	1
188	Development of piezoelectric nanostructures for cell stimulation. , 2017, , .		1
189	Microdevices for Cell Stimulation: Integrated Zinc Oxide Piezoelectric Nanostructures in Silicon Microparticles. , 2021, , .		1
190	Hopping Process in Majority Carrier Capture of Deep Centers in Semiconductors. Physica Scripta, 1987, 35, 717-720.	2.5	0
191	Boron implantation effects on Au: GaAs Schottky barrier. Vacuum, 1987, 37, 415-417.	3.5	0
192	Analytical Modeling of the Gold Diffusion Induced Modification of the Forward Current through P-N Silicon Junctions. Solid State Phenomena, 1997, 57-58, 525-0.	0.3	0
193	<title>Doping and structural properties for the phosphorous-doped polysilicon layers used for micromechanical applications</title>. , 1999, , .		0
194	<title>Mechanical stress in polysilicon layers and evaluation by a new procedure</title>. , 1999, 3893, 368.		0
195	Structural and Electrical Characterization of Ion Beam Synthesized and n-Doped SiC Layers. Materials Science Forum, 2001, 353-356, 591-594.	0.3	0
196	<title>Band-pass transimpedance read-out circuit for UHF MEMS resonator applications</title>. , 2005, , .		0
197	<title>Integrable silicon microsystem for three-dimensional flow focusing</title>. , 2005, , .		0
198	<title>MEMS with integrated CMOS read-out circuit based on sub-micrometric cantilevers array for multiple sensing (Invited Paper)</title>. , 2005, , .		0

#	ARTICLE	IF	CITATIONS
199	Design of a microinductive device integrated within a simple resonant differential filter for high sensitivity portable biodetectors. , 0, , .		0
200	Fabrication of electrostatic resonators with monocrystalline 3C SiC grown on silicon. , 0, , .		0
201	Fabrication and characterization of Co-Ni magnetic cantilevers. , 0, , .		0
202	Fabrication and Test of 3C-SiC Electrostatic Resonators. Materials Science Forum, 2007, 556-557, 949-952.	0.3	0
203	Towards a Microsystem of Multiple Production of Micro-Drops Manufactured on Silicon. , 2007, , .		0
204	Automated on-wafer characterization in micro-machined resonators: towards an integrated test vehicle for bulk acoustic wave resonators (FBAR). , 2007, , .		0
205	Analytical and finite-element modeling of a localized-mass sensor. , 2008, , .		0
206	Design and fabrication of Si technology microgenerators for vibrational energy scavenging. , 2009, , .		0
207	Microneedles electrodes for living cells. , 2009, , .		0
208	Comparative performance of static-mode ferrous MEMS gradiometers fabricated by a three-step DRIE process. Journal of Micromechanics and Microengineering, 2010, 20, 075006.	2.6	0
209	Electron microscopy of polymer-carbon nanotubes composites. , 2010, , .		0
210	In-parallel maskless fabrication of nanowire-based device array. , 2011, , .		0
211	Study of LCE nanocomposites through electron microscopy. , 2011, , .		0
212	Mechanical modeling of thermally actuated LCE-CNT composite. Proceedings of SPIE, 2011, , .	0.8	0
213	Micro-barcodes for biological applications. , 2011, , .		0
214	Charge storage and retention in electret dielectric layers for energy harvesting applications. , 2014, , .		0
215	Integration of PDMS microfilters and micromixers bonded onto APTES-functionalized polymeric films for size sorting and mixing of microparticles. , 2014, , .		0
216	SiNERGY, a project on energy harvesting and microstorage empowered by Silicon technologies. , 2015, , .		0

#	ARTICLE	IF	CITATIONS
217	From materials to devices: Bottom-up integration of nanomaterials onto silicon microstructures for thermoelectric and piezoelectric applications. , 2017, , .		0
218	Development of Hybrid Piezoelectric Microdevices for Bioapplications. , 2021, , .		0